

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	
Koichiro TANAKA)	Confirmation No. 9528
Application No. 10/769,820)	Examiner: Samuel Heinrich
Filed: February 3, 2004)	Group Art Unit: 1725
For: LASER IRRADIATION STAGE, LASER)	
IRRADIATION OPTICAL SYSTEM, LASER)	
IRRADIATION APPARATUS, LASER)	
IRRADIATION METHOD, AND METHOD OF)	
MANUFACTURING A SEMICONDUCTOR)	Date: October 17, 2007
DEVICE)	

AMENDMENT

United States Patent and Trademark Office
Customer Service Window, Mail Stop AF
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir:

In response to the Office Action mailed July 17, 2007, please amend the above-identified patent application as follows.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 10 of this paper.